Advanced Laser Cutting Equipment for n-Type Cells





¹<u>M. Grimm</u>, ²N. Chen, ³S. Harrison, ⁴L. Tous

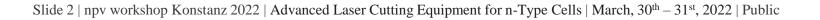
¹3D-Micromac AG (Germany), ²ISC Konstanz (Germany), ³CEA-INES (France), ⁴imec (Belgium)

npv workshop 2022, Konstanz

March, $30^{\text{th}} - 31^{\text{st}}$, 2022

Overview

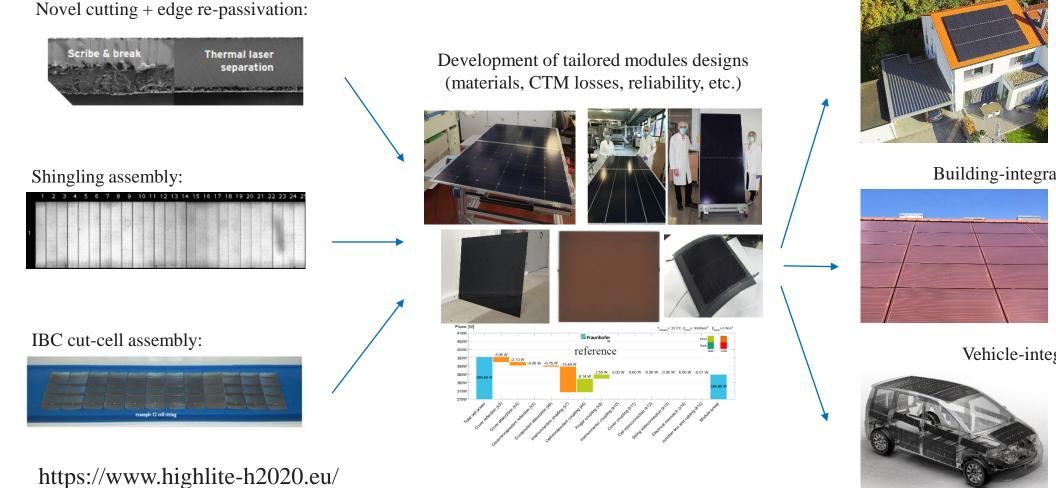
- H2020 HighLite project
- 3D-Micromac at a glance
- TLS-Dicing
- microCELL MCS
- Cell edge passivation on TLS diced SHJ solar cells
- Cell edge passivation on TLS diced IBC solar cells
- Summary





Approach in H2020 HighLite project

2) Develop novel equipment and processes for premium modules tailored for various applications (BAPV, BIPV, VIPV)



Building-applied PV (BAPV)



Building-integrated PV (BIPV)



Vehicle-integrated PV (VIPV)







Slide 3 | npv workshop Konstanz 2022 | Advanced Laser Cutting Equipment for n-Type Cells | March, 30th – 31st, 2022 | Public

3D-Micromac – Micromachining Excellence

We are the leading specialist in laser micromachining.

Our mission:

- Development and production of unique process and machine solutions for various high-tech markets
- Customer support from product development to high-volume production
- Enabling laser micromachining techniques for new devices
- Superior production efficiency and reliable process stability



"Our international customers place great value on future-oriented and user-friendly processes. Our solutions help them increase production efficiency and lower cost". *Uwe Wagner, CEO*



3D-Micromac – The Specialist in Laser Micromachining

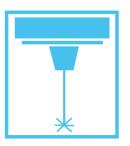




Services



Ma	ch	ine	Base



» Founded in 2002
» 190 employees
» Based in Chemnitz, Germany
» Branch offices in US, Taiwan,

China

 » Feasibility studies & process development in house
 » Production of limited lots and ramp up production
 » Worldwide sales & service network » > 600 installations worldwide

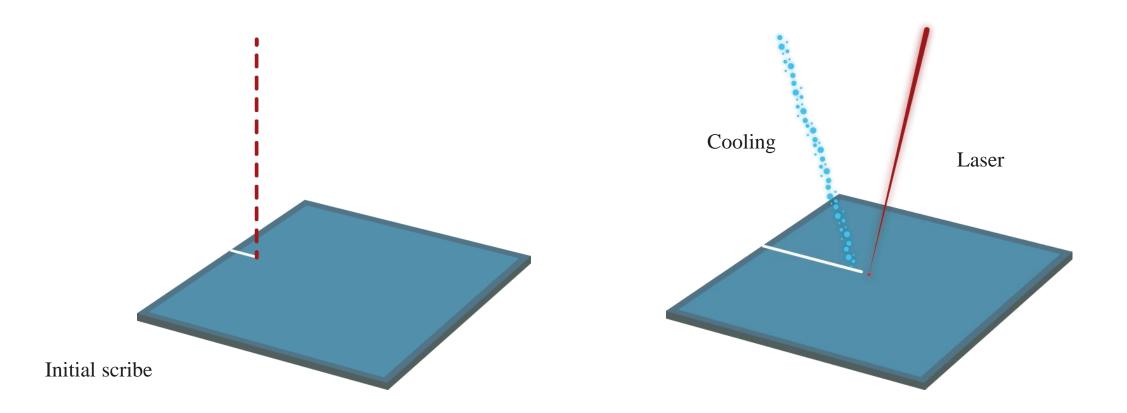
» > 100 systems in PV industry



3D-Micromacs Cutting Solution: Thermal Laser Separation (TLS-Dicing[®])

• Starting point defined by initial scribe

• TLS is a cleaving process, initiated by heat and immediate cooling



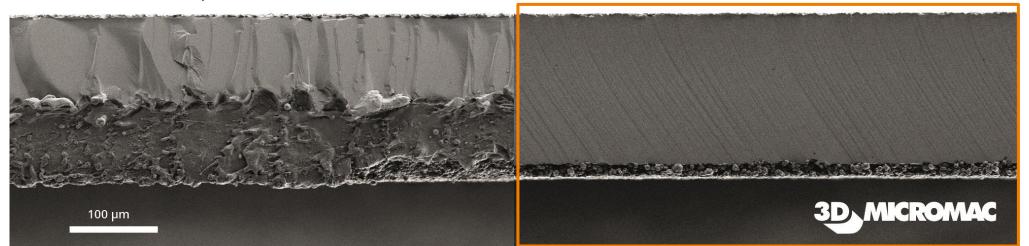


TLS-DicingTM vs. Scribe and Break – Results Breaking Edge

Cross sectional view on solar cell after cutting

Conventional process: scribe and break





→ Extensive chipping
→ Very rough structure

- \rightarrow Very smooth structure
- \rightarrow No chipping visible
- \rightarrow perfect surface for re-passivation

approaches

Slide 7 | npv workshop Konstanz 2022 | Advanced Laser Cutting Equipment for n-Type Cells | March, 30th - 31st, 2022 | Public



TLS-DicingTM vs. Scribe and Break

Comparison of Fracture Origin

EL images from module laminate test

Fracture Origin: Surface

ce 🗸 Edge

Full Cells (reference) Thermal Laser Separation (TLS) Laser Scribe and Cleaving (LSC) 10 830 27 630N 650N 690N 650 surface defects \rightarrow pads surface defects \rightarrow pads mostly edge defects \rightarrow cutting process

EL pictures after testing | brightness and contrast adjusted

→ Courtesy Fraunhofer CSP

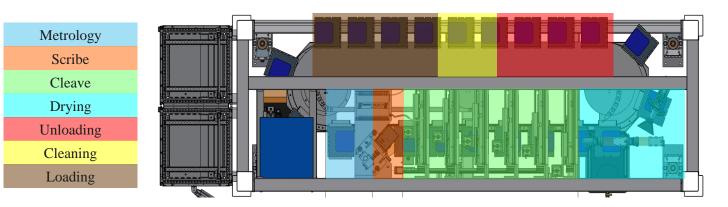


microCELL MCS

3D-Micromac's HighThroughput Shingling Tool

- Circulating chuck system with 22 carriers
- 4.6m x 1.4m x 2.0m (length x width x height)
- Format and pattern adjustments via flexible chuck design
- up to five process positions: exchangeable, retrofitable, expandable
 -> fully flexible from ½ cells to 1/6 cell stripes
- Wafer sizes up to M12
- Wafer recognition by camera
- Scanner-based initial scribe
- Cleave: adjustable on motorizes stages
- $v_{max} = 500 \text{ mm} / \text{ s}$
- $TPT_{max} = 6.400 \text{ wph}$
- available for demonstration and applications







microCELL MCS

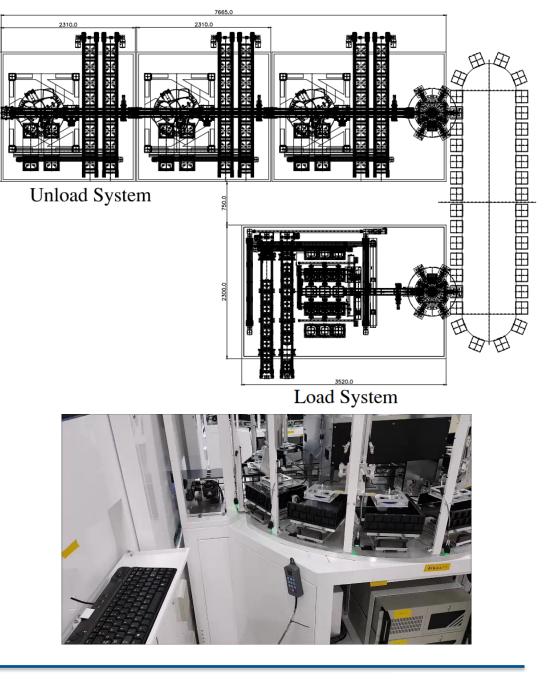
3D-Micromac's HighThroughput Shingling Tool

Load System

- rotary pick-and-place out of boxes
- buffer with 10 full cell boxes, fully automatic box change and transfer
- Wafer size up to M12

Unload System

- Modular system
- Upgrade unloading modules possible depending on the number of strips
- Buffer with 10 boxes, fully automatic box change and transfer, pick-and-place via Spider robots
- Wafer size up to M12

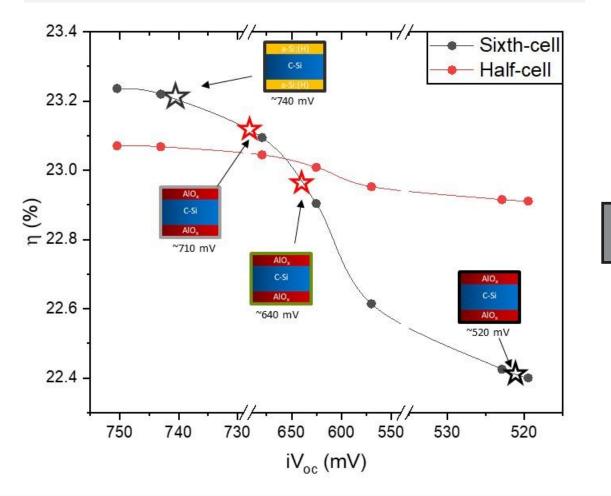




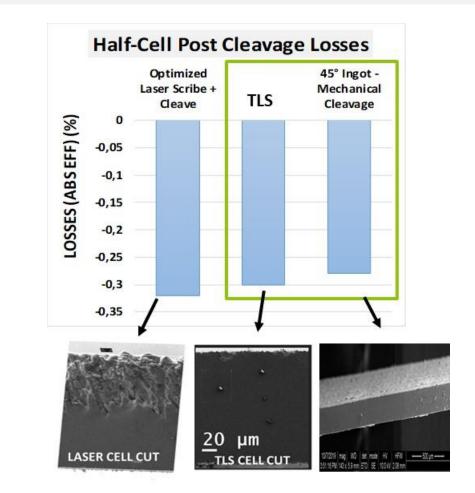
Cell edge requirements for SHJ & edge passivation



 ✓ High recovery potential achievable, but requires high-post-cut edge morphology quality



 ✓ Equally good morphological & electrical results obtained for TLS & Mechanical cleavage

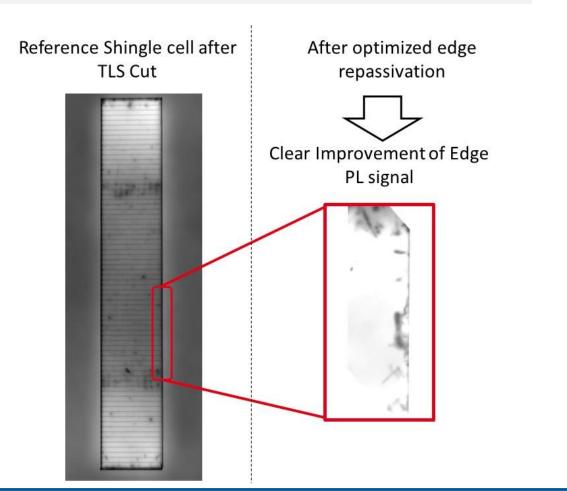




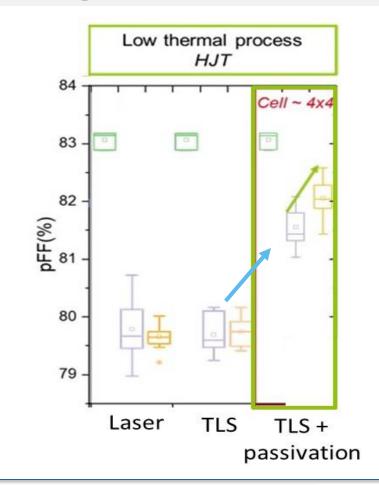
Promising Combination of TLS & Edge repassivation for Shingle cells



✓ PL confirmation of TLS good compatibility with proper post-cut edge passivation



 ✓ Electrical outputs: partial recovery of cell performances obtained for TLS cut & edge passivation combination





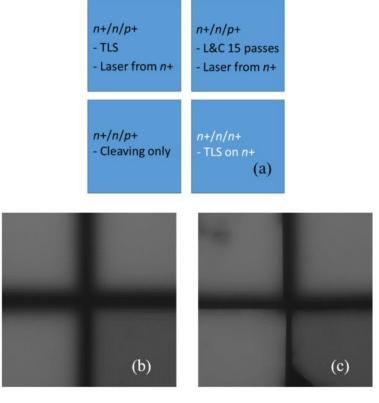
Repassivation of IBC Solar cells

On cell level

- Using high-resolution PL for characterization edge passivation
- Evaluated different cut techniques: TLS, L&C, and cleaving
- Equally good repassivation on TLS and cleaved samples, however, not stable yet

Reference: N. Chen, D. D. Tune, F. Buchholz et al., "Impact of Cut Edge Recombination in High Efficiency Solar Cells – Measurement and Mitigation Strategies." 38th EU PVSEC, 2021.





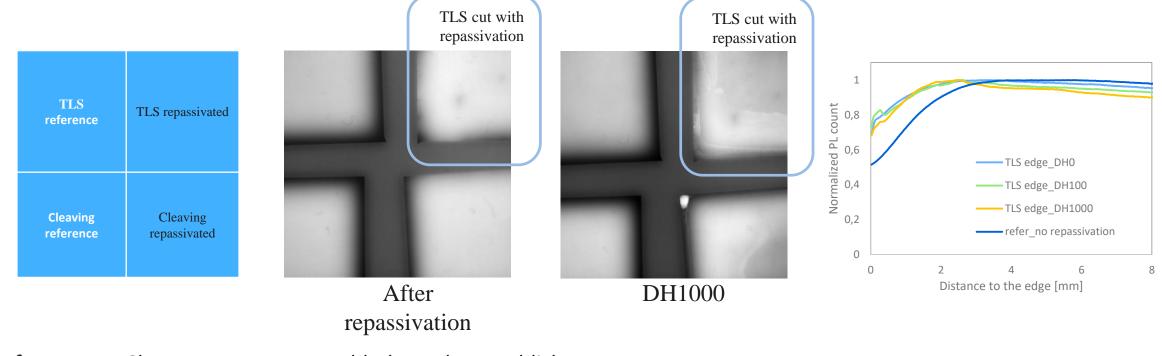
Repassivation samples locations (a), before repassivation (b) and after repassivation (c)

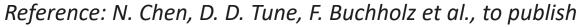


Repassivation of IBC Solar cells

on module level

- n+/n/p+ samples, with TLS or cleaving cut
- with Glass/backsheet and EVA encapsulation, the samples were immediately encapsulated after repassivation
- Repassivation is still good after Damp Heat 1000 hours







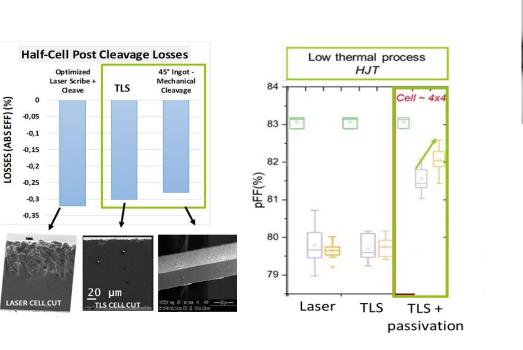


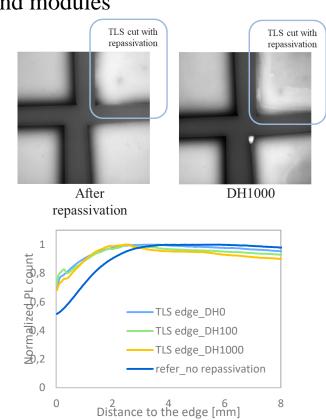
Summary

- High throughput tool with TLS process to cut cells in ¹/₂, 1/3 cells and shingles is available
- Flexible chuck design accept wafers up to M12



- excellent egde quality of TLS-Dicing is the key for efficient repassivation approaches
- Demonstrated for SHJ and IBC solar cells and modules





Acknowledgement:

This project has received funding from the European Union's Horizon2020 Programme for research, technological development and demonstration under Grant Agreement no. 857793.



Contact:

3D-Micromac Michael Grimm <u>grimm@3d-micromac.com</u> ISC Konstanz Ning Chen <u>ning.chen@isc-konstanz.de</u> CEA-INES Samuel Harrison <u>samuel.harrison@cea.fr</u> HighLite Loic Tous Loic.Tous@imec.be



